

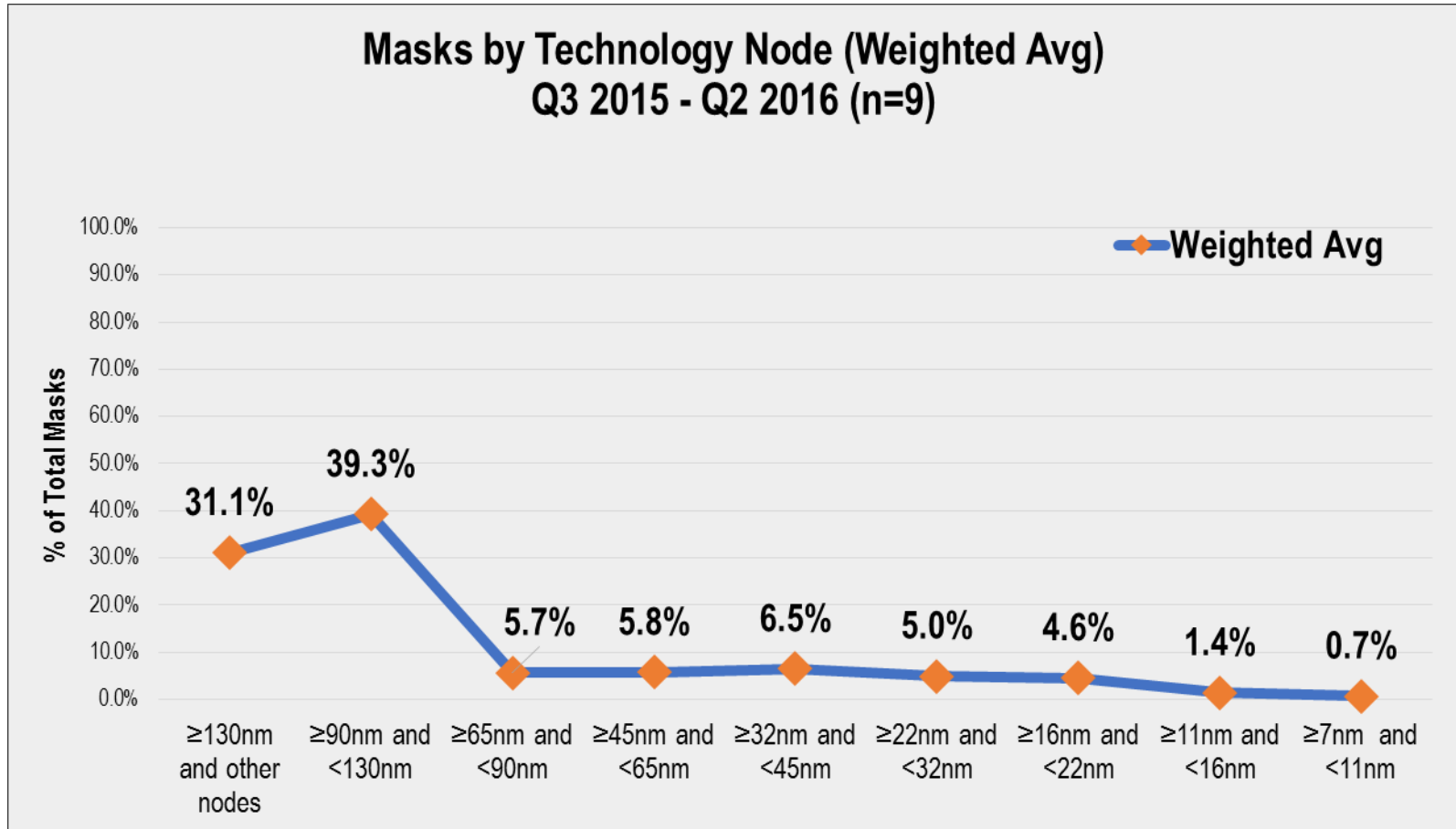
# The Mask Maker Survey 2016

- **2015: Members requested the eBeam Initiative to “fill the gap” that the SEMATECH survey had served through 2013**
  - 8 participating mask makers
  - AMTC, DNP, GLOBALFOUNDRIES, HOYA, Photronics, Samsung, SMIC and Toppan
- **2016: Thank you to the 10 participating mask makers**
  - AMTC, DNP, GLOBALFOUNDRIES, HOYA, Intel, PDMC, Photronics, Samsung, SMIC and Toppan
  - More survey questions to capture historical data from Q3 2015-Q2 2016

# 212,965 Masks Delivered by 9 Companies

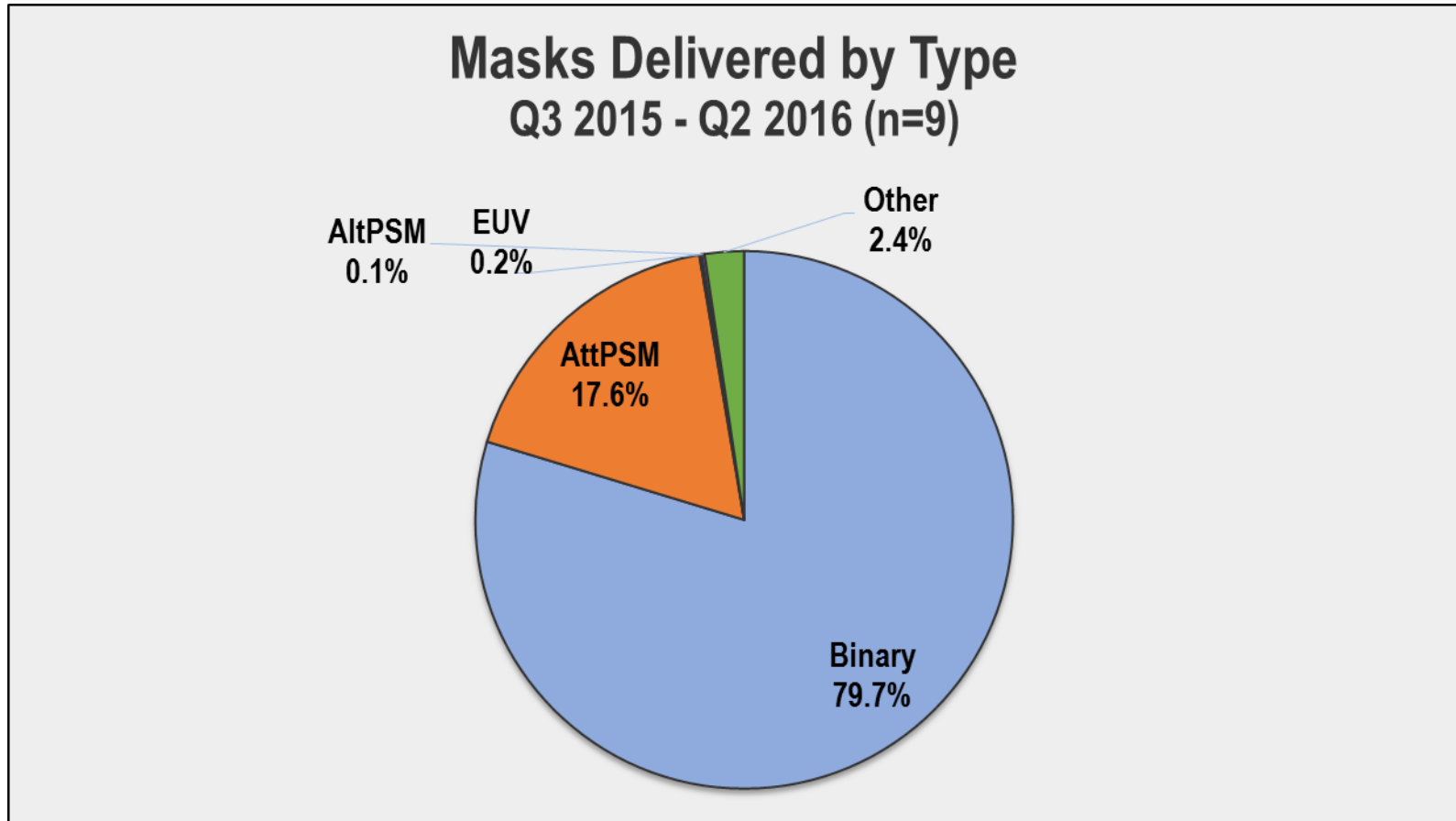


Q3 2015 – Q2 2016



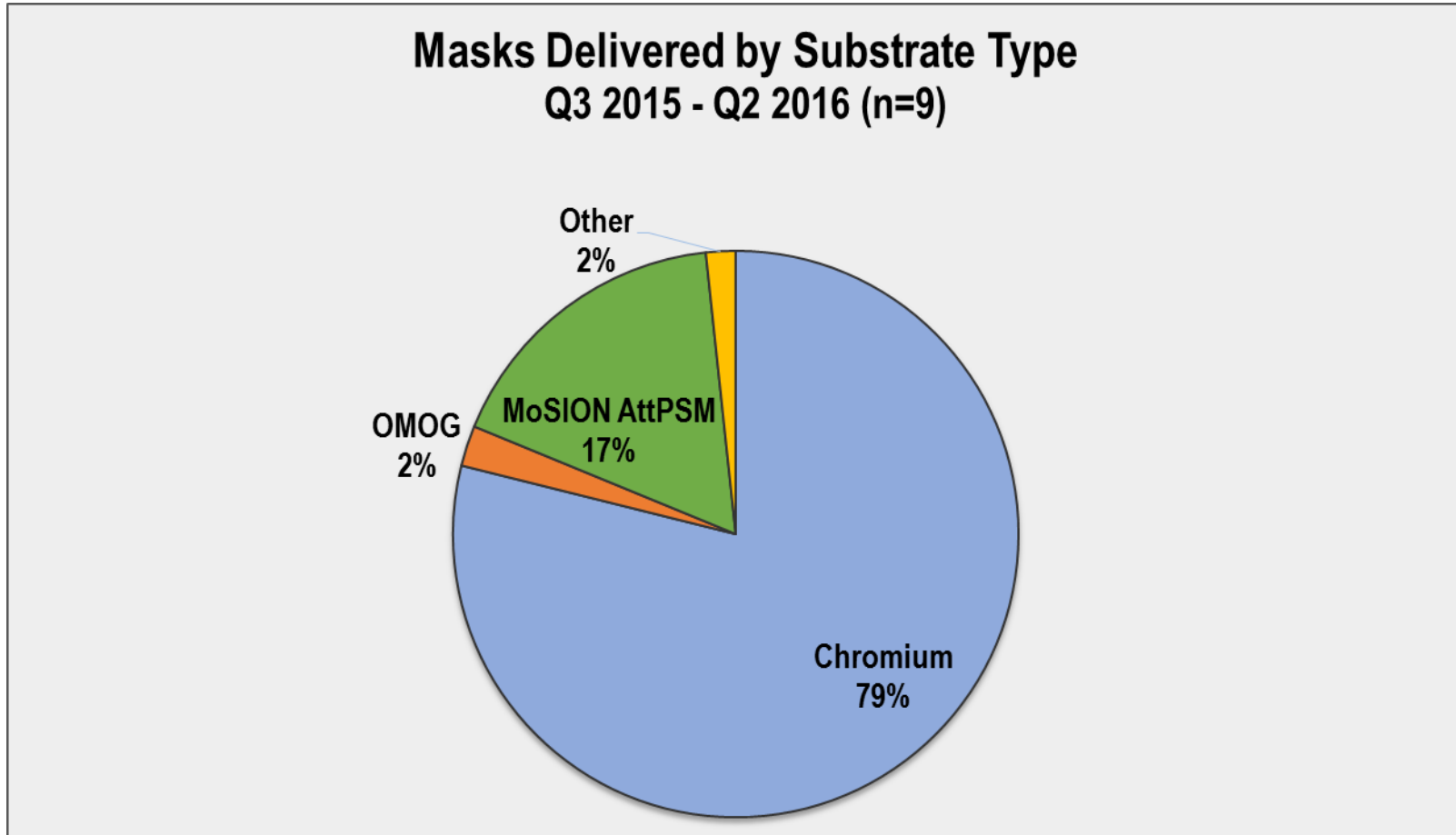
Q: What was the number of masks delivered in the last 12 months? Percent by technology node?

# Majority of Masks (79.7%) are Binary



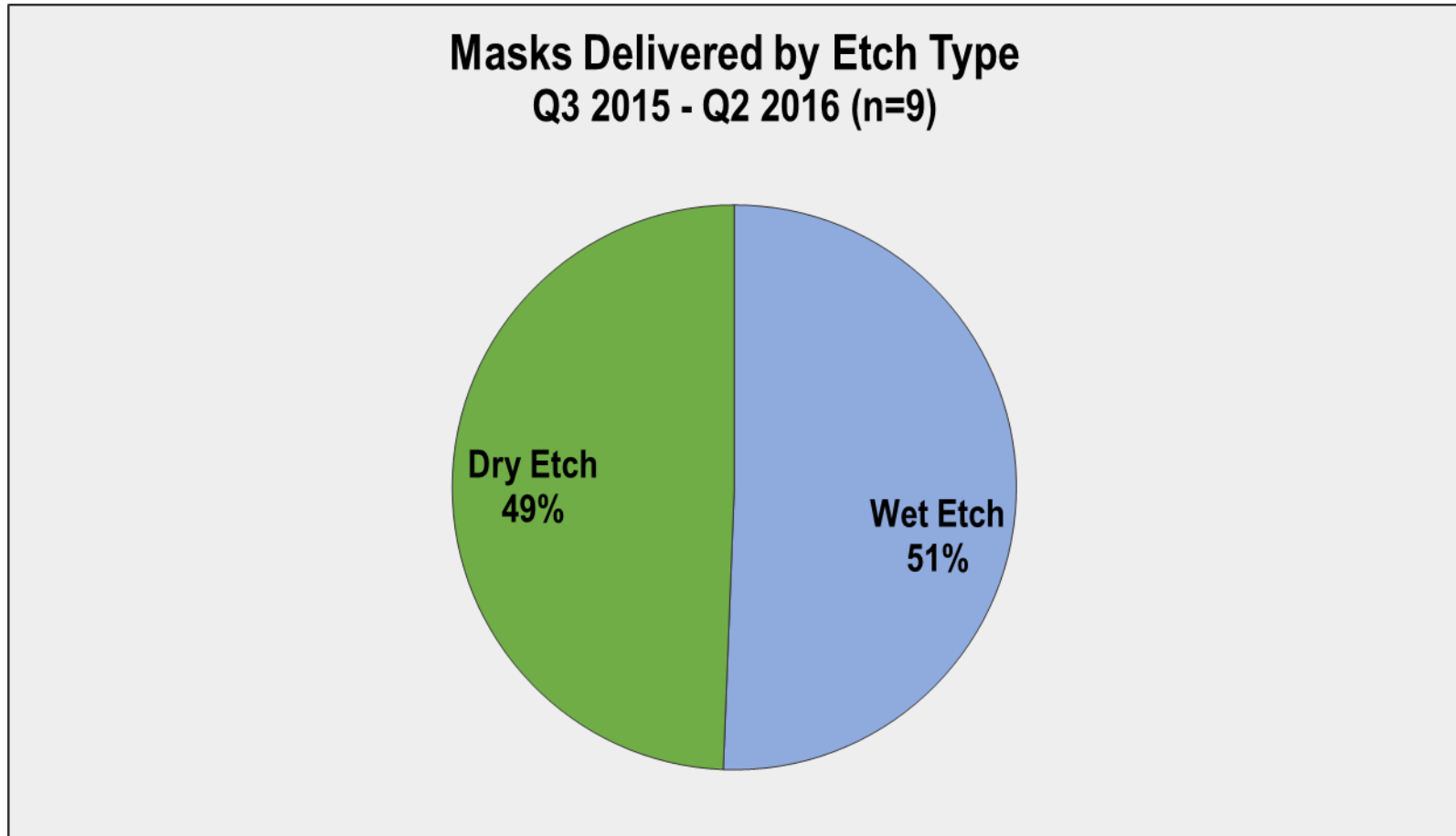
Q: What was the % by type?

# Chromium Substrates in the Majority (79%)



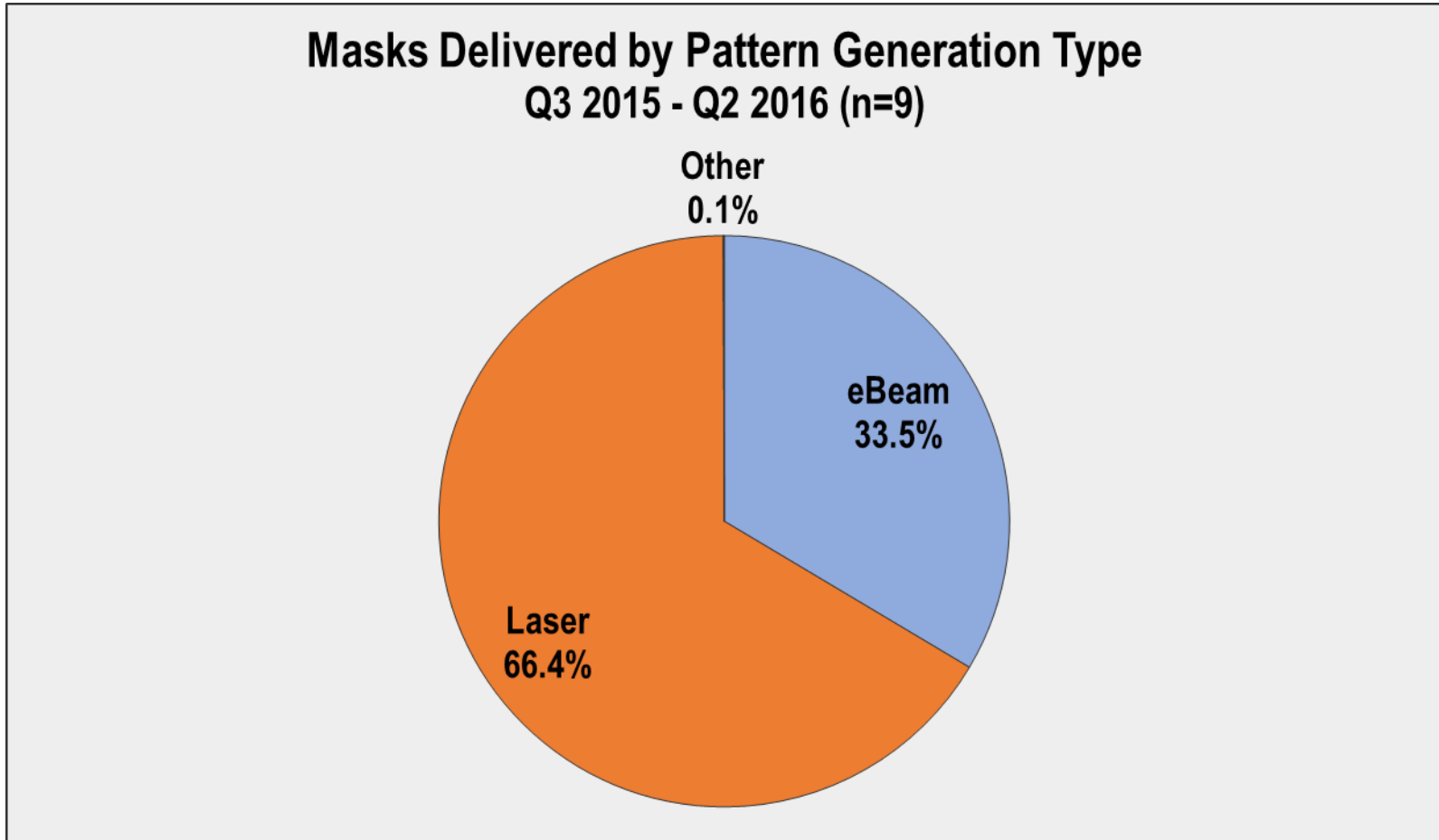
Q: What was the % by substrate type?

# Even Split in Etch Type Reported



Q: What was the % wet vs dry etch?

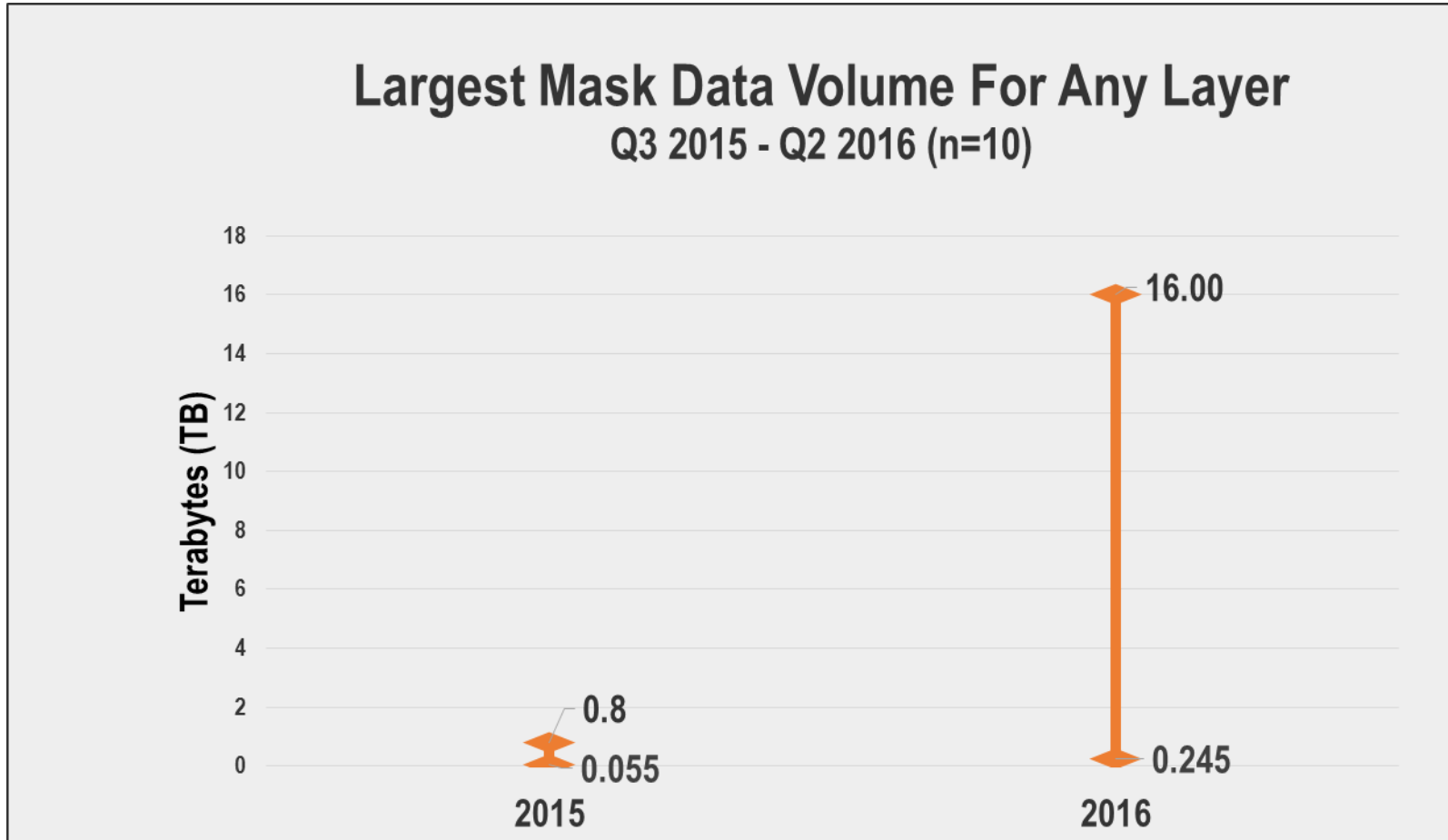
# eBeam Pattern Generation Used on 34%



Q: What was the % written by the following pattern generation: eBeam, Laser, other?

# Largest Data Volume Reported – 16 TB

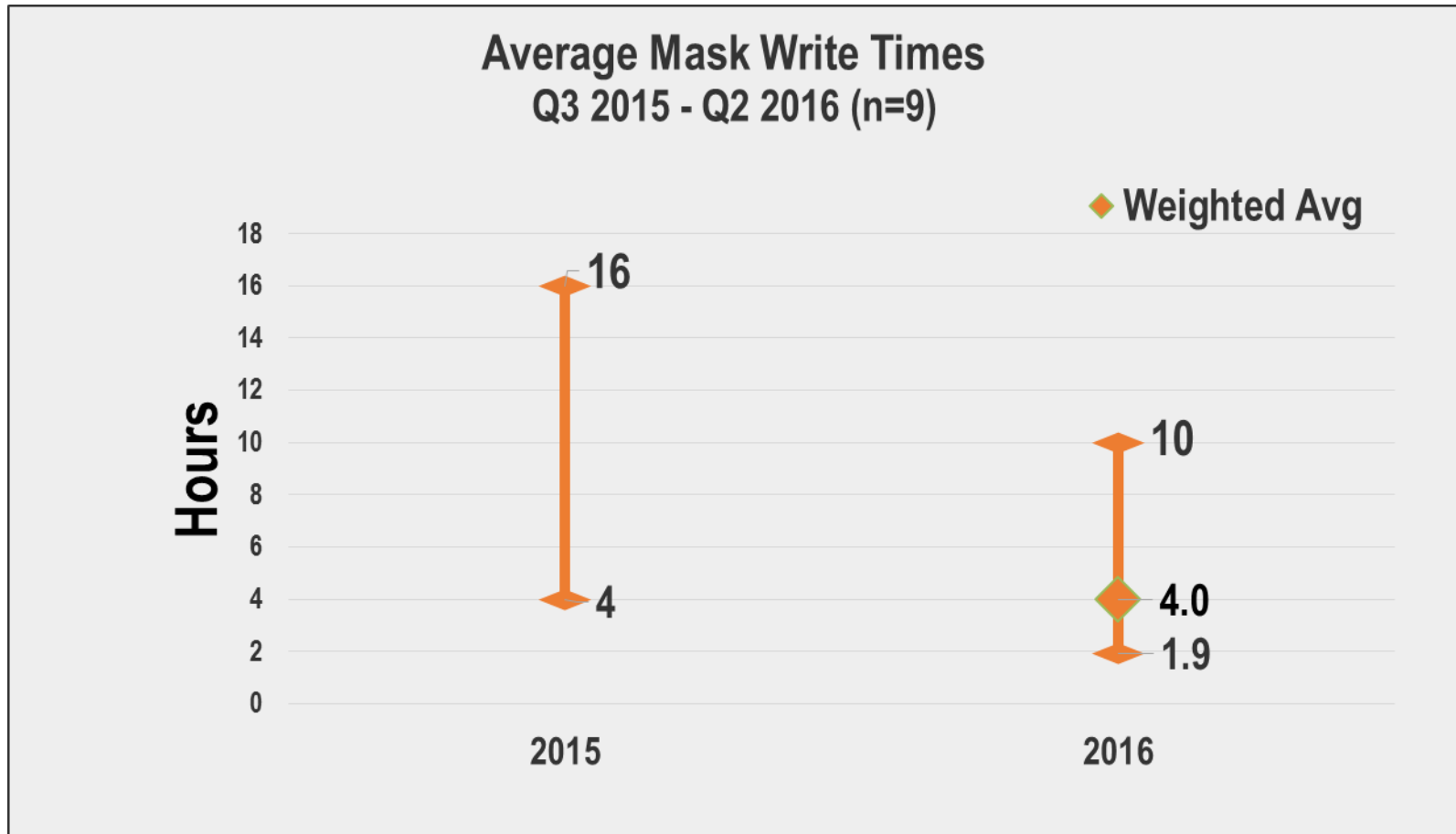
Could it be due to multi-beam?



Q: What was the largest data volume for any mask level?

# Average Mask Write Times Decreased

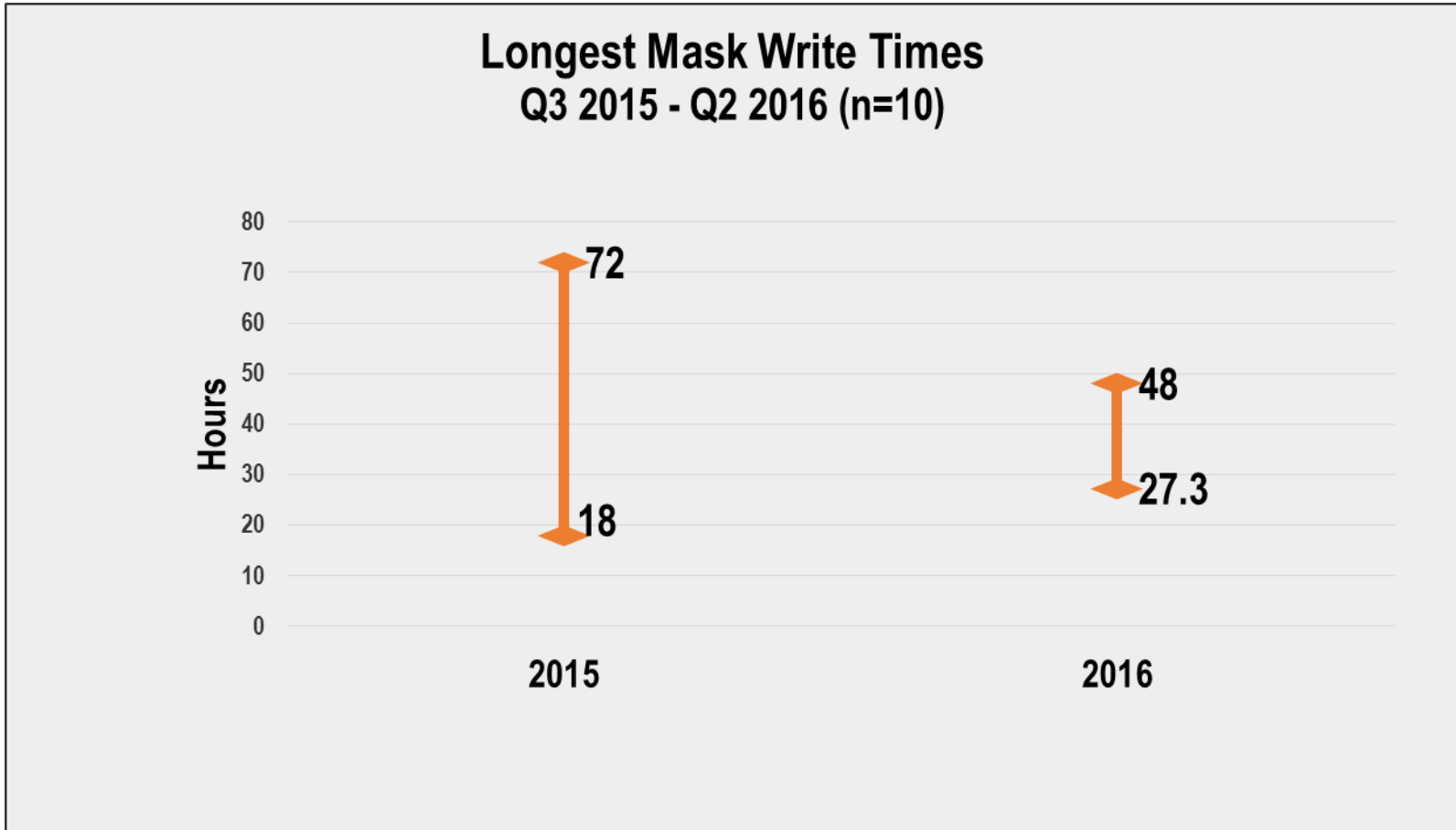
2016 span down to 1.9-10 hours; 4 hours weighted average



Q: What was the average write time over the past 12 months?



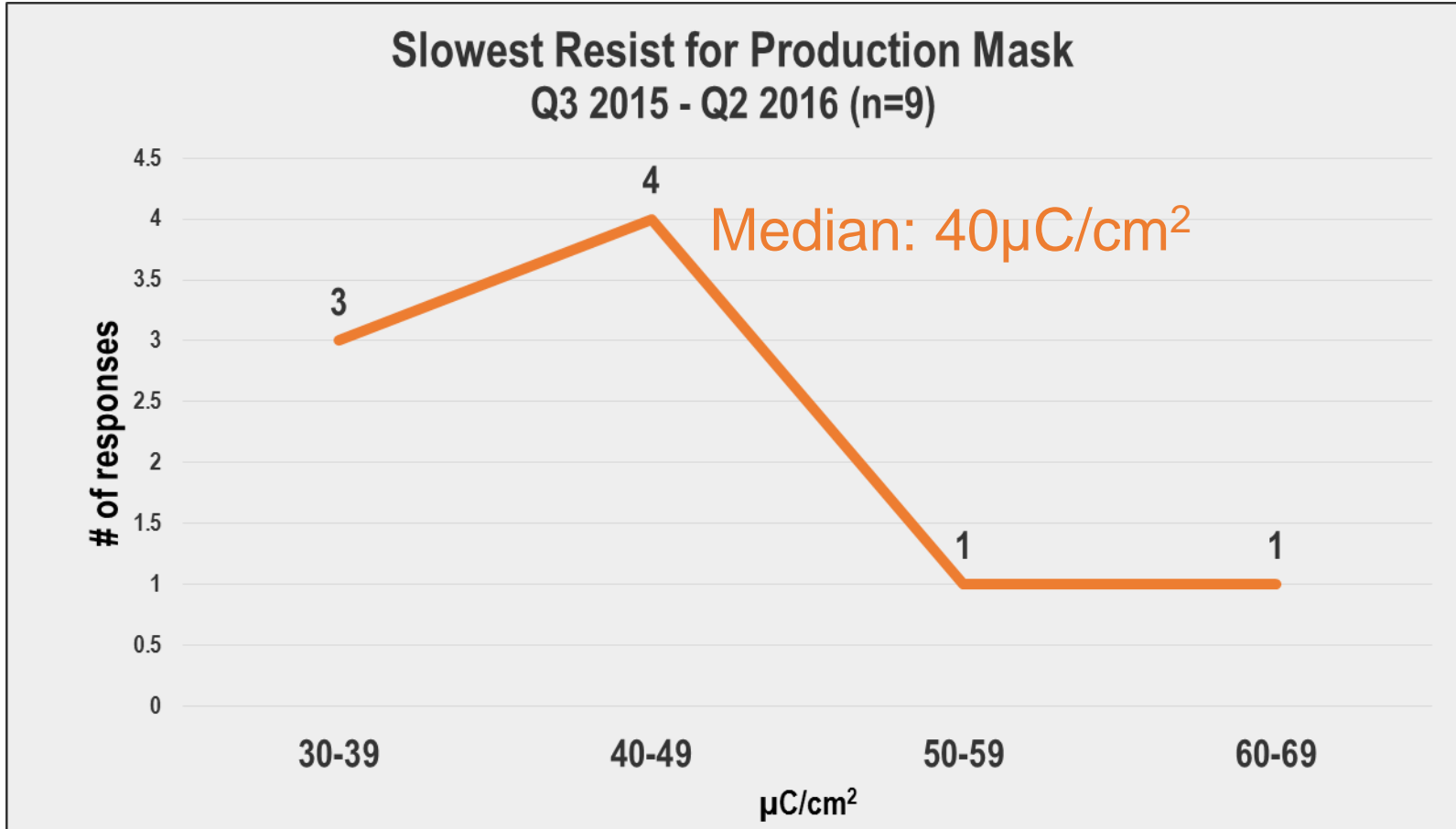
# Longest Write Time Reported – 48 Hours



Q: What was the longest write time over the past 12 months?

# Resist Usage Spans 30-69 $\mu\text{C}/\text{cm}^2$

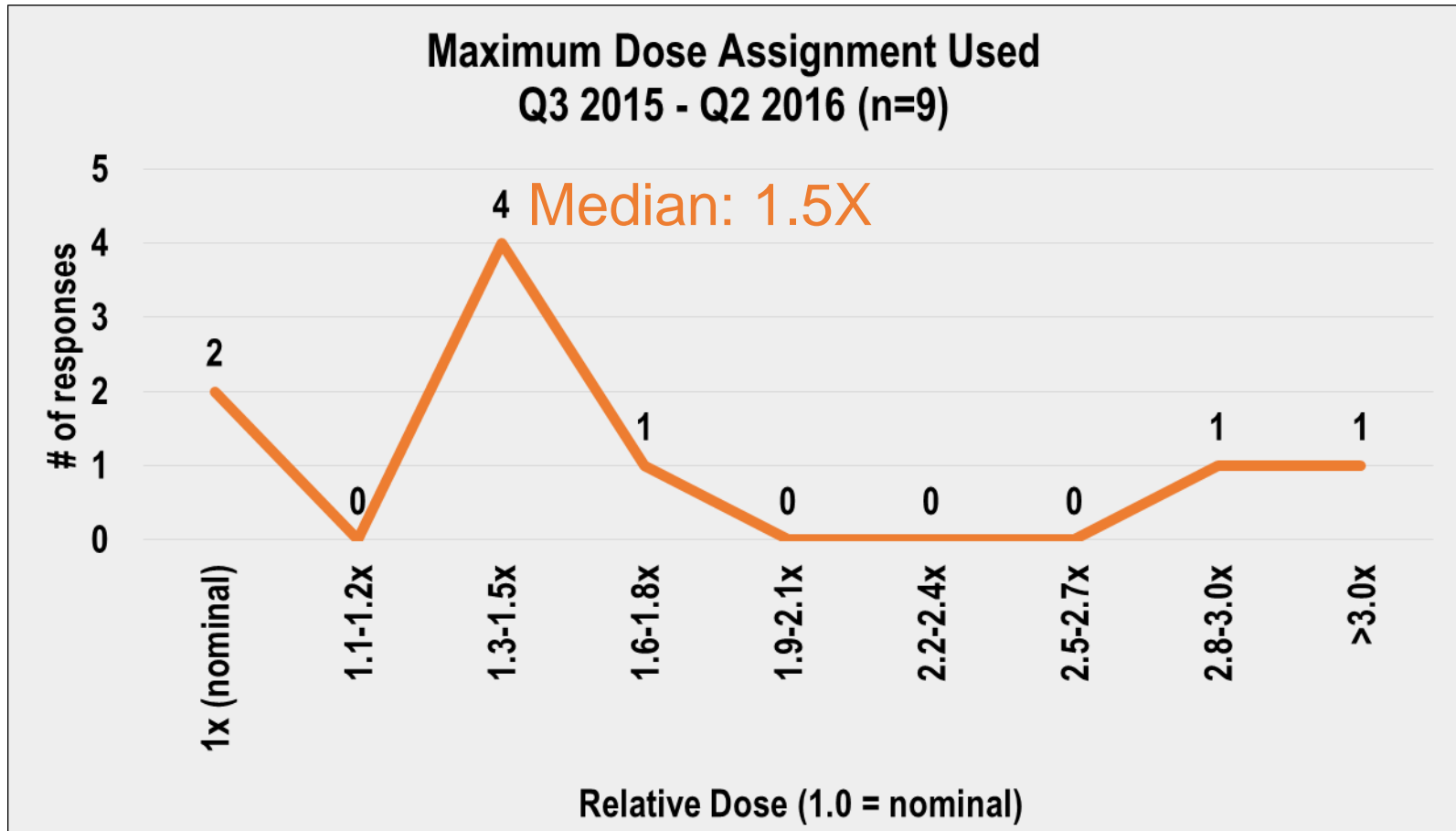
Majority (4) in 40-49 $\mu\text{C}/\text{cm}^2$  range



Q: In the past year, what was the slowest resist that was used for a production mask intended for production wafer manufacturing?

# Dose Assignment Reported by 7 out of 9

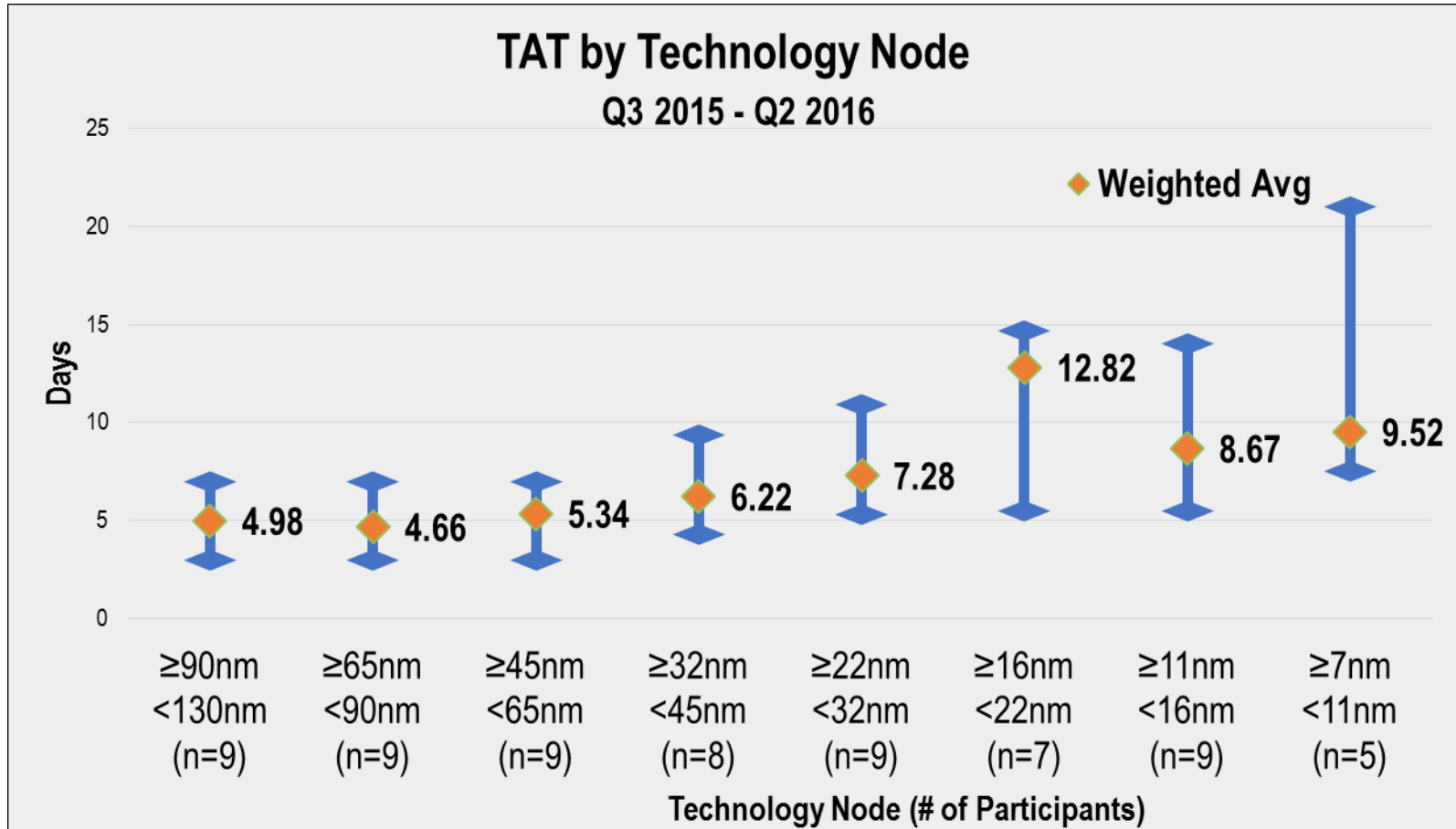
5 reported between 1.3x to 1.8x, 2 reported  $\geq 2.8x$



Q: In the past year, what was the max dose assigned to shots in the data provided to the mask writing machine? Please answer relative to 1.0 (nominal dose)

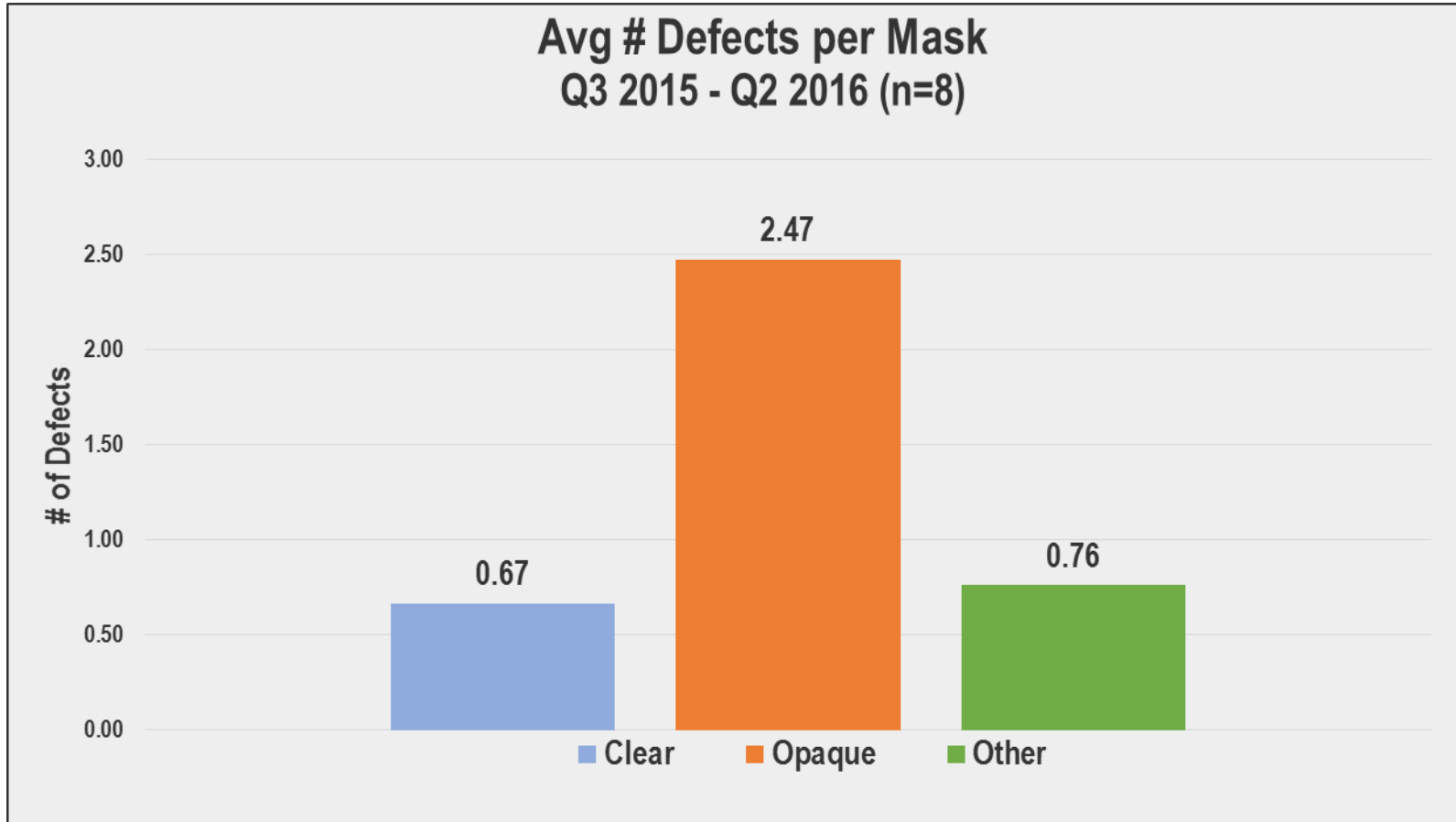
# TAT Approaching 10 Days

## Did TAT increase dramatically at 16-20nm?



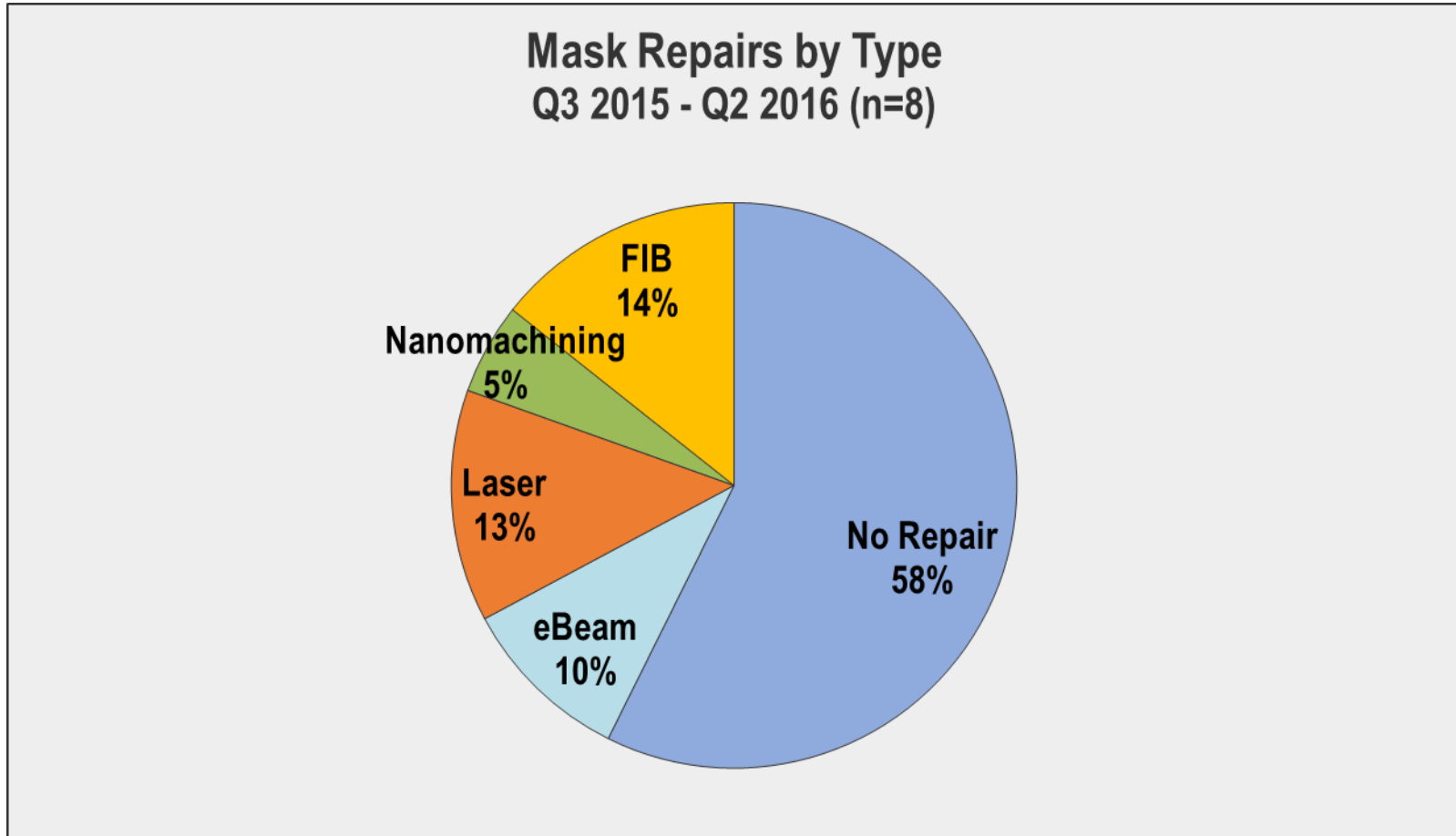
Q: What was the average turn-around-time (TAT) by technology node?

# Most Mask Defects Are Opaque



Q: What was the average number of defects per mask for the past 12 months?

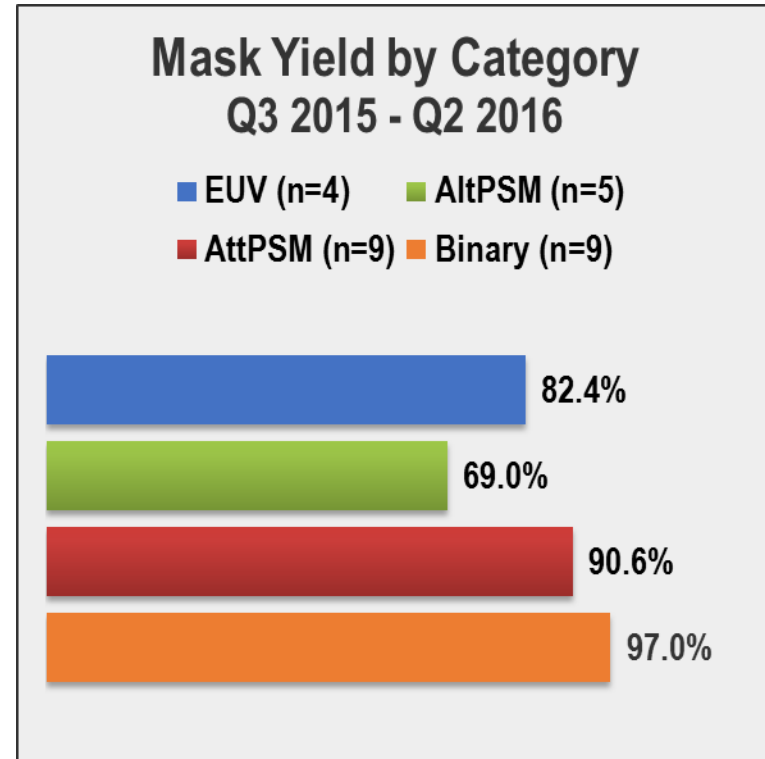
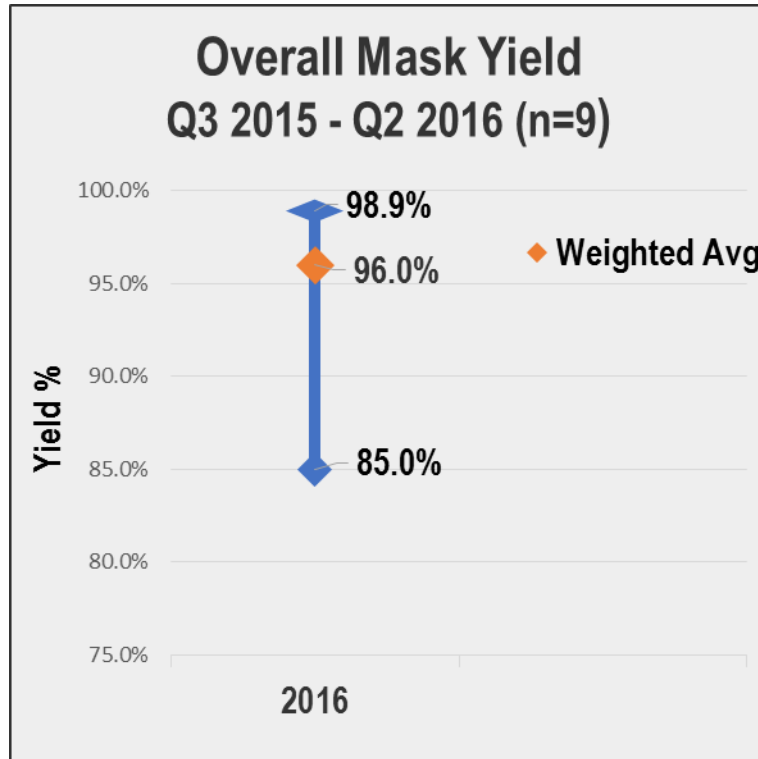
# FIB Used Most for Mask Repairs at 14.3%



Q: What was the percentage of masks repaired by...no repair, eBeam, laser, nanomachining, FIB?

# Average Mask Yield of 96% Reported

EUV mask yield on average >80% (4 reported)



Q: What was your overall mask yield for the past 12 months?

Q: What was your percent mask yield by category?

# Strong Participation in 2016 Mask Survey

- **10 mask makers in total – merchant and captive**
- **Largest data set reported to be 16 TB**
- **But mask write times decreased significantly with a weighted average of 4 hours**
- **TAT continues to increase, approaching 10 days**